



(11) **EP 2 818 928 B8**

(12) **CORRECTED EUROPEAN PATENT SPECIFICATION**

(15) Correction information:
Corrected version no 1 (W1 B1)
Corrections, see
Bibliography INID code(s) 72

(51) Int Cl.:
G03F 7/20 (2006.01) **G03F 9/00** (2006.01)
G01B 11/27 (2006.01) **H01L 21/68** (2006.01)

(48) Corrigendum issued on:
30.11.2016 Bulletin 2016/48

(45) Date of publication and mention
of the grant of the patent:
28.09.2016 Bulletin 2016/39

(21) Application number: **14179101.2**

(22) Date of filing: **24.08.2010**

(54) **Exposure method, exposure apparatus, and device manufacturing method**

Belichtungsverfahren, Belichtungsapparat sowie Verfahren zur Herstellung einer Vorrichtung

Procédé d'exposition, appareil d'exposition et procédé de fabrication d'un dispositif

(84) Designated Contracting States:
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB
GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO
PL PT RO SE SI SK SM TR

(30) Priority: **25.08.2009 US 236704 P**
20.08.2010 US 860097

(43) Date of publication of application:
31.12.2014 Bulletin 2015/01

(60) Divisional application:
16166162.4 / 3 098 655

(62) Document number(s) of the earlier application(s) in
accordance with Art. 76 EPC:
10752443.1 / 2 470 961

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EP 2 818 928 B8